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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:

**Hitoshi KATO, et al.**

Serial No. : 10/066,627

Filed : February 6, 2002

Art Unit : 2822

Examiner : Maria F. Guerrero

For : A Precleaning Method of Precleaning a Silicon Nitride Film Forming System (as amended)

**LETTER WITH PROPOSED DRAWING CHANGES**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Applicants submit this Letter pursuant to *M.P.E.P.* § 608.02(r), in order to propose a change to original Fig. 6 in this patent application. The proposed change is as follows:

In Fig. 6, add the designation --Prior Art--.

The proposed change is illustrated in red in the attached copy of Fig. 6 as originally filed.


No new matter is contained in the proposed drawing change.

The Examiner's approval of this proposed drawing change is respectfully requested.

Respectfully submitted,

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By:

  
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